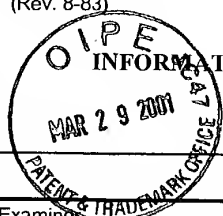


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FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
Alr	58-091676	05/31/1983	JP			Full Eng

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner Initial	
Alr	Nakazawa et al., "17.3: Lightly Doped Drain TFT Structure for Poly-Si LCDs", 1990, pp. 311-314, SID 90 Digest
Alr	Morozumi et al., "5.2 Low Temperature Processed Poly Si TFT and it's Application to Large Area LCD", 1986, pp. 196-199, R&D Dept. Seiko Epson Corp. Nagano, Japan Dislay
Alr	325105, "Enhanced Adhesion to Glass Substrates Using Tantalum Oxide Adhesion Layer", May 1991, pp. 369, Research Disclosure, No. 325, Havant GB, XP229725
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Examiner Harold Schultz Date Considered 8/29/00

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

03/19/2001